

GANPAT UNIVERSITY									
FACULTY OF ENGINEERING & TECHNOLOGY									
Programme		Bachelor of Technology				Branch/Spec.		Electronics and Communication Engineering	
Semester		VII				Version		1.0.0.0	
Effective from Academic Year			2026-27			Effective for the Batch admitted in			July 2023
Course Code		2EC71PE09		Course Name		Introduction to MEMS			
Teaching Scheme					Examination Scheme (Marks)				
(Per week)	Lecture (DT)		Practical (Lab.)		Total		CE	SEE	Total
	L	TU	P	TW					
Credit	3	0	1	0	4	Theory	40	60	100
Hours	3	0	2	0	5	Practical	30	20	50
Pre-requisites									
Course Outcomes									
On successful completion of the course, the students will be able to:									
CO1	Explain the fundamentals, classification, and applications of Micro-Electro-Mechanical Systems (MEMS).								
CO2	Describe MEMS materials, microfabrication processes, and basic mechanical structures used in MEMS devices.								
CO3	Analyze the working principles of common MEMS sensors and actuators used in industrial and consumer applications..								
CO4	Identify MEMS-based applications in automotive, biomedical, communication, and consumer electronics domains.								
Theory Syllabus									
Unit	Content								Hrs.
1	Introduction to MEMS Overview of MEMS, evolution of MEMS technology, comparison of MEMS with IC and macro systems, advantages and limitations of MEMS, classification of MEMS devices, MEMS applications in daily life								9
2	MEMS Materials and Microfabrication MEMS materials: silicon, polymers, metals, piezoelectric materials, crystal structure of silicon, micromachining concepts, bulk micromachining, surface micromachining, LIGA process (overview), packaging of MEMS devices								9
3	Mechanical Structures and Transduction Mechanisms Basic mechanical elements: cantilevers, beams, membranes, diaphragms, springs, basic mechanical parameters (stress, strain, deflection – qualitative), transduction mechanisms: piezo-resistive, capacitive, piezoelectric, thermal and optical transduction (basic concepts)								9
4	MEMS Sensors MEMS pressure sensors, accelerometers, gyroscopes, microphones, temperature sensors, gas sensors, working principles, block diagrams, specifications and applications								9
5	MEMS Actuators and Applications MEMS actuators: electrostatic, thermal, piezoelectric actuators, RF MEMS (overview), Bio-MEMS (overview), automotive MEMS applications, medical and healthcare MEMS, consumer electronics MEMS, future trends in MEMS technology								9
Practical Content									
Practical assignments and tutorials are based on the above syllabus.									
Text Books									
1	Tai-Ran Hsu, MEMS and Microsystems: Design and Manufacture, McGraw-Hill								
Reference Books									
1	Stephen D. Senturia, Microsystem Design, Springer								

2	Marc Madou, Fundamentals of Microfabrication and Nanotechnology, CRC Press
ICT/MOOCs Reference	
1	NPTEL: Introduction to MEMS – IIT Madras / IIT Kharagpur
2	NPTEL: Microfabrication and MEMS

Mapping of CO with PO and PSO:															
	P O 1	P O 2	P O 3	P O 4	P O 5	P O 6	P O 7	P O 8	P O 9	P O 1 0	P O 1 1	P O 1 2	P S O 1	P S O 2	P S O 3
CO1	3	1	1	0	0	0	0	1	1	0	0	3	0	1	0
CO2	2	1	1	0	0	0	0	1	1	0	0	2	0	1	0
CO3	3	3	3	2	2	0	0	1	1	0	0	2	1	1	0
CO4	2	3	2	2	2	0	0	2	2	0	0	2	2	2	0